



YES-1224P Chemical Vapor Deposition (CVD) System

With Plasma for Total environmental Control Over Surface Preparation

Specifications

Hardware	
Clean Room Compatibility	Class 10
Chamber Material	316L stainless steel
Chamber Size	40.6 cm (W) x 46 cm (D) x 40.6 cm (H) (16"x 18"x 16")
Overall System Dimensions	103.5 cm (W) x 111.1 cm (D) x 114.46 cm (H) (40.75" x 42.75" x 45.06") Note: Light tower increases height 30 cm (11.81")
Loading	4 removable internal stainless steel shelves; 16 available configurations
Filter	0.5 Micron® filter
Mass Flow Controllers	Optional, up to 4 gas mixing
Software	
Number of Recipes	6 CVD, 4 Plasma
Range of Exposure Time	0-999999
Resolution of Timer Setting	1 second
Performance	
RF Plasma Frequency	40 kHz
RF Plasma Power	100-1000 Watts
Operation Temperature	Ambient to 205 °C
Uniformity	± 5 °C during dwell after stabilization period
Chemical Usage	Typical process 3-5 ml
Chemical Volume Control	Control down to 0.1 ml
Process Gas Inputs	1
Plasma Gas Inputs	3
Vent Gas Consumption	10 SCF run average
Reactant Gas Consumption	4.2 X 10 ⁻³ SCF (based on standard process: 170°C @ 1000W w/20 SCFM pump)
Wafer Throughput	Typically 1-2 loads/hr; varies by process
Slide Throughput	600 slides/hr for CVD
Additional	
Safety	Audible and visual alarms; redundant over-temp monitoring
Power Requirements	230V, 30 amps, 50 Hz, 1 phase, 5400 Watts (European) 208V, 30 amps, 60 Hz, 1 phase, 4835 Watts (Domestic)
Power Supply	Automatic Frequency Tuning
Auto LN2 Refill (option)	200-240 VAC ± 10%, 50-60 Hz, 4.2 amps maximum, 1 phase, 850 watts maximum
Shipping Weight, Crated (approx.)	499 kg (1100 lbs)
Crate Dimensions	106.7 (W) x 137.2 (D) x 114.3 cm (H) (42"x 54"x 45")



Contact Us

When you're ready to run process tests, a demonstration can be arranged using your chemicals and samples. Call +1 925-373-8353 (worldwide), 1-888-YES-3637 (US

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Yield Engineering Systems, Inc. 203-A Lawrence Drive, Livermore, California, USA 94551-5152
Tel: +1 925 373 8353 | Fax: +1 925 373 8354 | www.yieldengineering.com